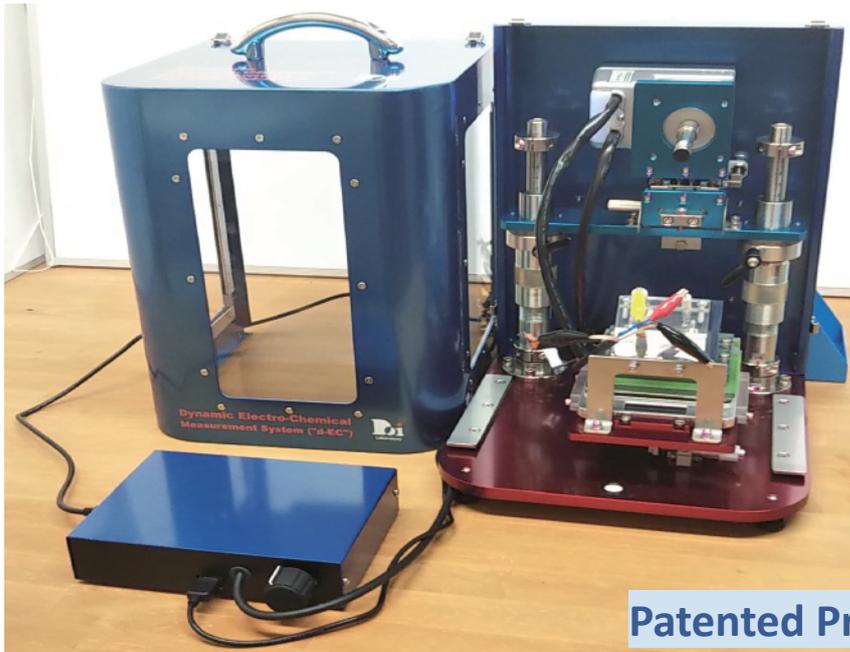


Dynamic Electro-Chemical measurement system "d-EC"

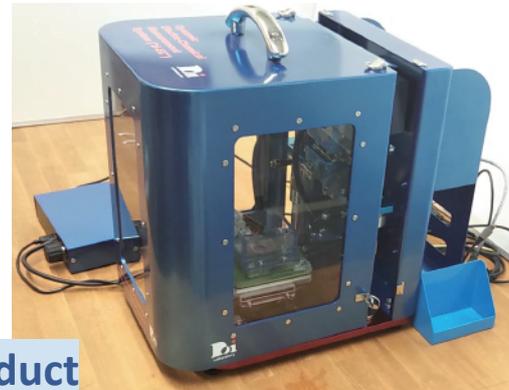


Unique system for Slurry study & development

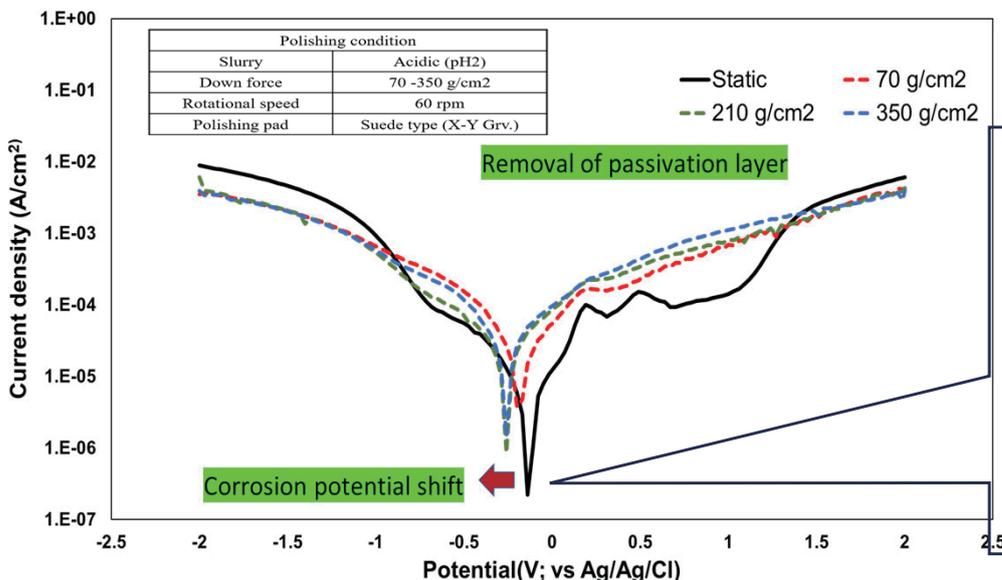
- Compact and easy use system
- Dynamic measurement with good repeatability
- LSV(Tafel), OCP, "Static-Dynamic" repeated measurement



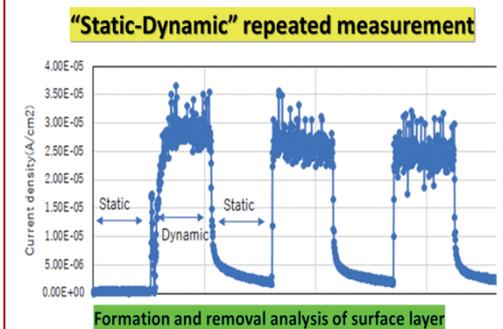
Polishing configuration	
Rotational speed	0 - 1000 rpm
Down force	0 - 1000 g/cm ²



Patented Product



Dynamic analysis



Example of Cu Tafel Plots under the different polishing pressures & 'Static-Dynamic' repeated measurement

Design & Manufacture: Doi Laboratory Inc.,

authorized distributor



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